

**REPLY UNDER 37 C.F.R. § 1.116
EXPEDITED PROCEDURE
GROUP ART UNIT 2818**

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Applicant(s) : LAERMER et al.
Serial No. : 10/524,610
Filed : August 11, 2005
For : LAYER SYSTEM HAVING A SILICON LAYER AND A
PASSIVATION LAYER, METHOD FOR CREATING A
PASSIVATION LAYER ON A SILICON LAYER AND ITS USE
Art Unit : 2818
Examiner : HO, Hoang Quan Tran
Confirmation No. : 9981

I hereby certify that this correspondence is being electronically
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S I R:

This paper is filed in response to the Final Office Action dated October 9, 2007 in
connection with the above-captioned application.

Remarks begin on page 2 of this paper.